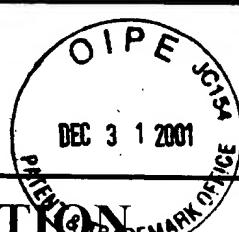


INFORMATION DISCLOSURE STATEMENT BY APPLICANT					ATTY. DOCKET NO.	SERIAL NO.	
					F070	09/840,558	
APPLICANTS Gerlach, van der Mast, and Scheinfein					FILING DATE	GROUP ART UNIT	
					April 23, 2001	2881	
U.S. PATENT DOCUMENTS							
*Examiner Initial	Cite No.	Patent Number	Issue Date	Patentee	Class	Subclass	Filing Date (if appropriate)
PB	A	4,126,781	11/21/78	Siegel	250	281	
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PB	C	4,810,880	3/7/89	Gerlach	250	305	
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PB	F	6,218,664	4/17/01	Krans et al.	250	310	RECEIVED
FOREIGN PATENT OR PUBLISHED FOREIGN PATENT APPLICATION							
	Cite No.	Document Number	Date	Country	Class	Subclass	Translation Yes <input checked="" type="checkbox"/> No <input type="checkbox"/>
OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)							
*Examiner Initial	Cite No.						
PB	H	BAUER, E., KOZIOL, C., LILIENKAMP, G., SCHMIDT, T.; "Spectromicroscopy in a Low Energy Electron Microscope", <u>Journal of Electron Spectroscopy and Related Phenomena</u> , Vol. 84, pp. 201-209(1997).					
PB	I	KRANS, J.M. and van ROOY, T.L., "A Miniature Low Voltage SEM with High Resolution", <u>Microscopy and Microanalysis</u> , Vol 5, Supplement 2, pp 2-4, Portland, OR, Aug 1-5, 1999.					
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*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



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APPLICANTS Gerlach, van der Mast, and Scheinfein					FILING DATE April 23, 2001	GROUP ART UNIT 2881	
U.S. PATENT DOCUMENTS							
*Examiner Initial	Cite No.	Patent Number	Issue Date	Patentee	Class	Subclass	Filing Date (if appropriate)
FOREIGN PATENT OR PUBLISHED FOREIGN PATENT APPLICATION							
	Cite No.	Document Number	Date	Country	Class	Subclass	Translation
							Yes No
OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)							
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<i>Pf</i>	L	POSTEK, MICHAEL T., "The Scanning Electron Microscope," <u>Handbook of Charged Particle Optics</u> , edited by Jon Orloff, CRC Press LLC, 1997; Ch. 9, pp.363-382.					
<i>Pf</i>	M	PURCELL, E.M., "The Focusing of Charged Particles by a Spherical Condenser," <u>Phys. Rev.</u> , 54, pp. 818-826 (1938).					
<i>Pf</i>	N	SAR-EL, H.Z., "Criterion for Comparing Analyzers," <u>The Review of Scientific Instruments</u> , Vol. 41, No. 4, 561-564 (1970).					
EXAMINER <i>Paul Lingo</i>	DATE CONSIDERED <i>12/13/02</i>						

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